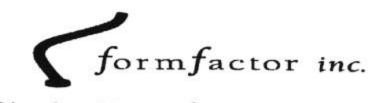
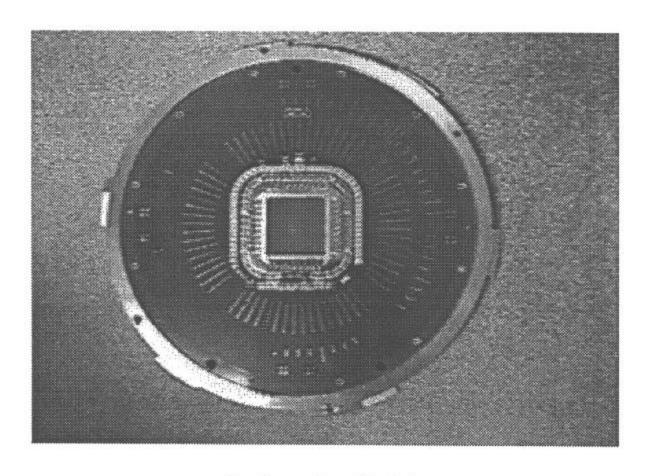


WaferProbeTM System

By Larry Levy

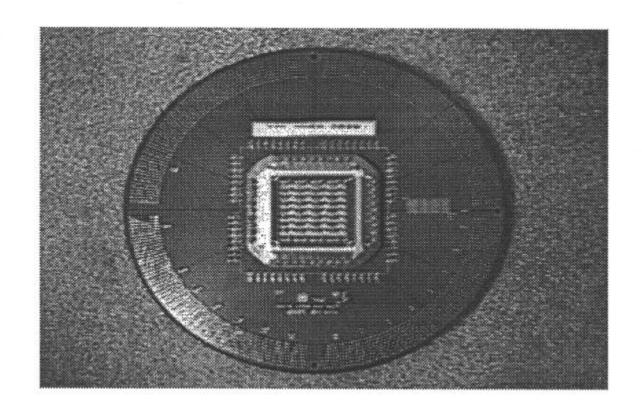


High Performance C 4 Probe Card





High Performance 4 X 8 Multiple DRAM Probe Card





WaferProbe TM System

- Microspring Technology
 - Semiconductor Processing
 - Existing Equipment (customized)
 - Patented and Patent Pending Technology



WaferProbeTM

- Multiple Applications
 - Al Pad Probing
 - C 4 Array Probing
 - Parallel Testing (Multiple Die)
 - At Speed Testing
 - At Temperature Testing

formfactor inc.

Typical WaferProbe Specifications

C4 Planarity (Z axis):

 \pm 7.5 μ (0.3 mils), 3 sigma < 13 μ (0.5 mils) min to max

Aluminum Tip Planarity:

 \pm 13 μ (0.5 mils)

Alignment (X-Y axis)

 \pm 13 μ (0.5 mils), 3 sigma < 25 μ (1 mil) min to max

Actual OT Required

50μ (2 mils) for C4

35μ (1.5 mils) for Al

125µ (5 mils) max for both

Temperature Range

0 - 85 °C Tested (0 - 150 °C Expected)

Probe Length

C4: 1.5 mm (60 mils), Al: 2.3 mm (90 mils)

Probe Pitch

125 µ (LOC), 200µ Periph, design dependent

242 μ (C4), 225 μ late '97

Probe Tip Dimensions

C4 Ball: 125 µ diameter

Al Pad: "Pyramid" contact, 10μ sq. x 50μ tall

Typical Electrical Characteristics

Probe Tips

 Parasitic Inductance < 1nH

 Contact Resistance < 0.5 Ohms

 Current Load >1 amp

Probe Cards

 Impedance 50 Ohms

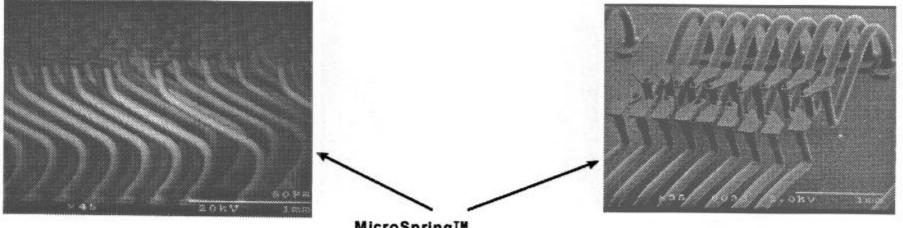
 Decoupling < 100 mils from

probe

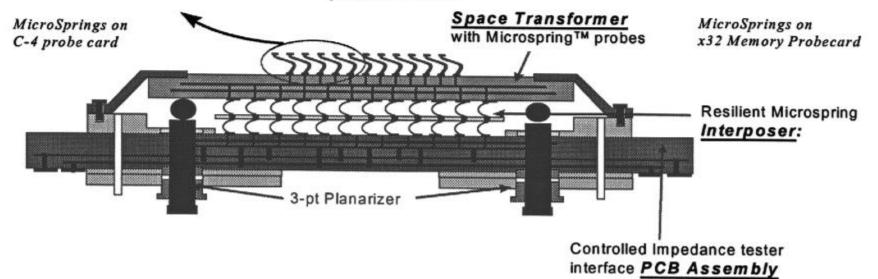
 Bandwidth >1 GHz

 Rise & Fall Times < 350 ps

FormFactor's WaferProbeTM System

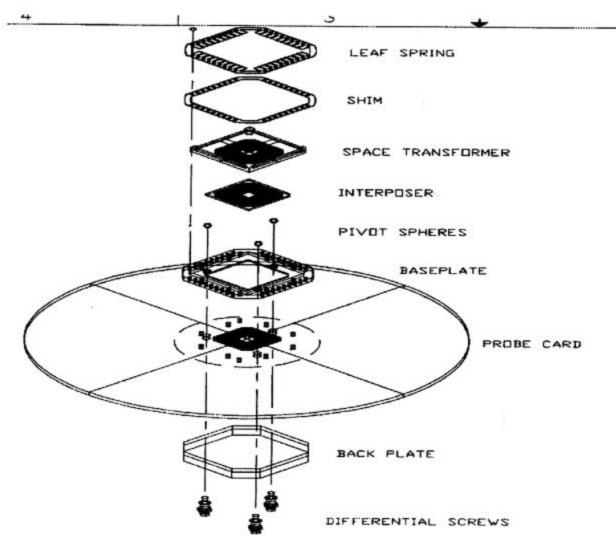


MicroSpring™ probe elements:



Southwest Test Workshop

WaferProbe Construction formfactor inc.





• Space Transformer w/ MicroSprings

- High performance, multilayer ceramic
- 50Ω impedance, distributed ground & power planes
- Decoupling capacitors added for high frequency bypass



WaferProbe[™] Components

Interposer

- Provides compliant z-axis, demountable connection for Space Transformer to PCB
- Double-side MicroSprings on High Temp Material
- 2000 Interconnect Lines--->4000 Future

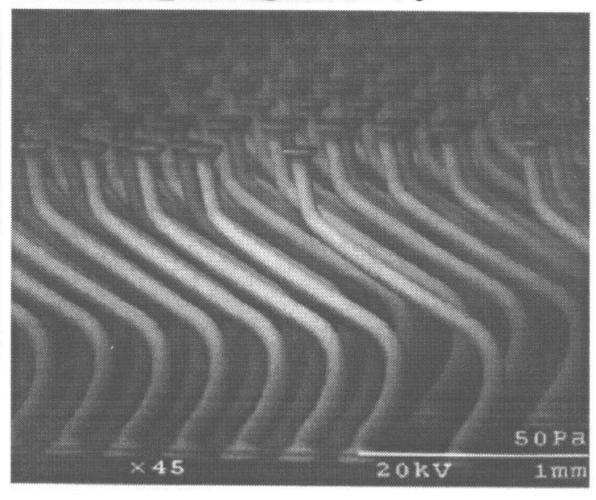
PCB Assembly

 Provides connection to tester, discrete components, Planarization Mechanism



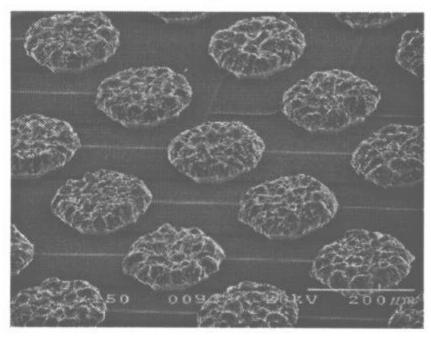
C4 MicroSpring Array

- Individually compliant springs
- Customizable Tips
- Capable of >250K touchdowns
- >1GHz bandwidth
- m X n Matrix, 2.25" max OD
- Programmable scrub characteristics
- No probe marks





C4 Pad: No Reflow Required



Unreflowed C4 Pad

After 10 Probes

Unreflowed C4 Pad Before Probe

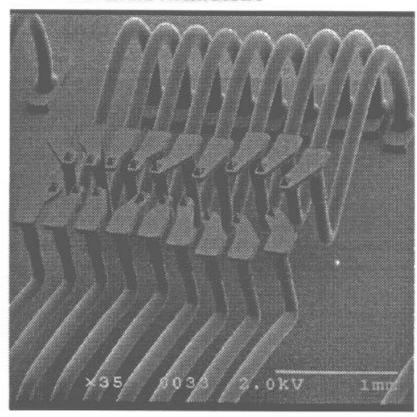
Southwest Test Workshop



Multi-Die Memory Probe Card

SEM photo of 1312 pin probe card for x32 16Mbit DRAM

- Capable to simultaneous x32 probing of DRAM or Flash devices
- Capable of >250K touchdowns (>8M devices)
- >1GHz bandwidth, capable of testing SDRAMs and RAMBUS/Synclink DRAMS @ speed
- m X n Matrix, 2.25" max OD
- Programmable scrub characteristics
- Probe mark <1/5 the size of conventional technology

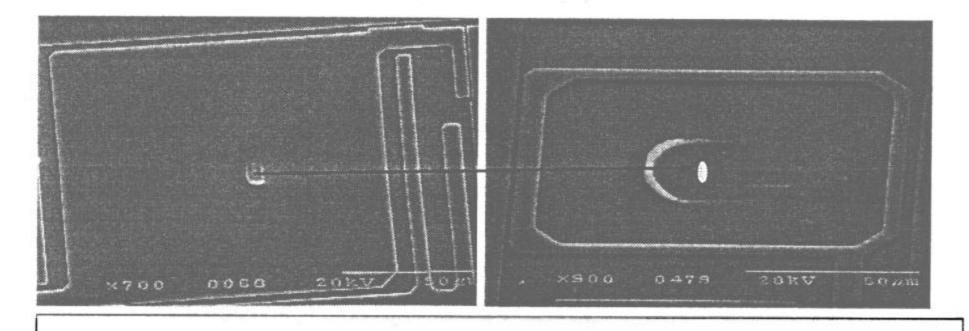




FormFactor Scrub Mark

FormFactor "Pyramid"
Probe Mark on Al

Tungsten Probe Mark on Al

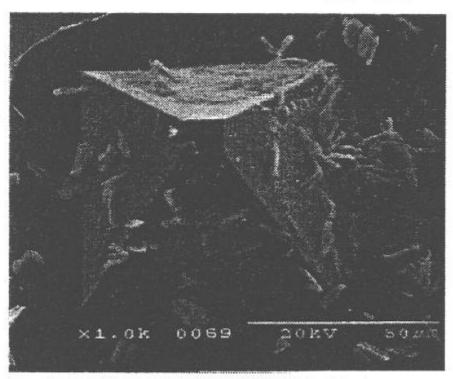


Magnification not Equivalent

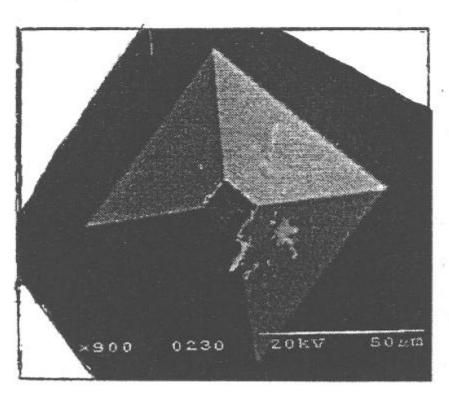


Pyramid Tip Wear and Cleaning

Tip Wear after 53K Cycles



Before cleaning



After cleaning & 500 TD



WaferProbeTM Status

x32 Memory Probe Cards:

- x32 cards running on production floor
 - 1312 pin card delivered (8x4, 32 in parallel)
 - Production setup, planarization, API inspection
 - Assembly Verification
 - Probe process (overdrive, etc.)
 - Cleaning methodology



WaferProbeTM Status

x32 Memory Probe Cards:

Performance

Card Type	Wafers per Unit Time	Yield	
8x1	1	1.000	
8x2	1.5	1.000	
FFI 8x4	2.8	1.003	



For	rmFactor	Cobra	Membrane	Tungsten Needle
Production Qualified	✓	✓	No	✓
Delivered x32 Memory Card	✓	No	No	✓
Full Array C4	✓	✓	✓	No
Low/No Maintenance	✓	✓	No	No
Eliminates C4 Reflow Step	✓	No	No	No
$> 1 \text{GHz}$ Bandwidth, 50 Ω	✓	No	✓	No
Individually Compliant Tips	✓	✓	No	✓
Photo-Defined Tip	✓	No	✓	No
Low Contact Force (< 7 gr)	✓	No	No	✓
Automatic Assembly	✓	No	✓	No
TCE Matched to Silicon	✓	✓	No	No
Z-Axis Planarity < 8 μ	✓	No	✓	No
X-Y Axis Alignment <13 μ	✓	No	✓	No